

Ion-induced epitaxy in Fe⁺ implanted SiO₂/Si: synthesis and optical characterization of FeSi₂ nanoparticles

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Abstract – FeSi₂ nanoparticles have been synthesized by ion-beam-induced epitaxial crystallization (IBIEC) of Fe⁺ implanted SiO₂/Si(100) followed by thermal treatment. As evaluated by Micro-Raman scattering spectroscopy and Transmission Electron Microscopy, upon annealing at 700 °C / 1h occurs a transition from metallic γ to semiconductor β phase in the recrystallized sample (Fig. 1). Photoluminescence spectroscopy measurements at 2K revealed strong emissions with different intensities and morphologies in the region 0.7 - 1.1 eV (Fig. 2). The physical origins of the distinct luminescence peaks were discriminated in terms of intrinsic emission of β -FeSi₂, optically active defect-centers in Si and intrinsic substrate emissions (excitonic complex).

Semiconducting silicides are of significant interest for silicon-based optoelectronics, optical interconnects and optical communications technologies. Among the transition-metal silicides, FeSi₂ is the unique that owns a semiconducting phase (β) and two distinct metallic phases (α and γ). In particular, the semiconducting β -FeSi₂ is a promising material for photodetectors, light emitters and solar cells devices, due to value of the energy gap, which gives rise to photoresponse in the near-infrared region at about 1.55 μ m.

We have synthesized and investigated the optical properties of FeSi₂ nanoparticles produced by ion-beam-induced epitaxial crystallization (IBIEC) in SiO₂/Si(100) n-type substrates. For this, Fe⁺ ions were implanted at cryogenic temperature (\sim 90 K) in two steps: i) 70 keV at the fluence of 5×10^{15} cm⁻² and ii) 40 keV at the fluence of 3×10^{15} cm⁻². This implantation process produces an amorphous silicon layer of \approx 115 nm thickness that was subsequently recrystallized by high energy irradiation with Si⁺ ions at 600 keV with the target at 350 °C.

By Micro-Raman Scattering Spectroscopy (μ RSS) we have identified the vibrational properties and thermal stability of the distinct FeSi₂ phases. Moreover, we show that annealing at T = 700 °C / 1h (in a gas atmosphere 95% N₂ - 5% H₂) leads to complete phase transition from the metastable γ to the β phase. Our Transmission Electron Microscopy (TEM) results corroborate the μ RSS characterization.

Photoluminescence (PL) measurements at 2 K showed only excitonic complex emissions from Si substrate in the as-IBIEC sample. After 700 °C annealing, a broad band appearing at \sim 0.79 eV can be attributed the intrinsic emission from β -FeSi₂. However, optical absorption spectra (300 K) near the fundamental absorption edge of β -FeSi₂ indicated indirect allowed transition. A phonon structure corresponding to the emission and absorption component was clearly observed.

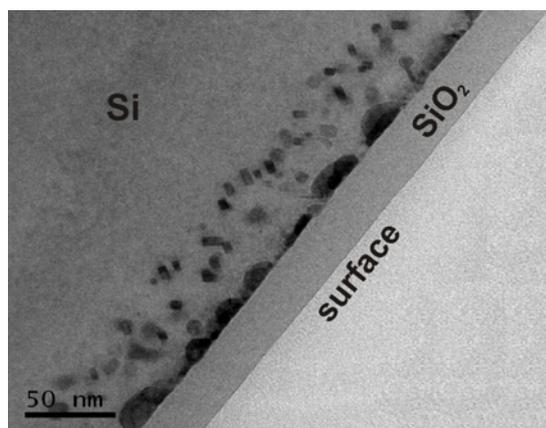


Figure 1: Cross section TEM image (700 °C annealed sample) showing the β -FeSi₂ precipitates close to the SiO₂/Si interface within the Si matrix.

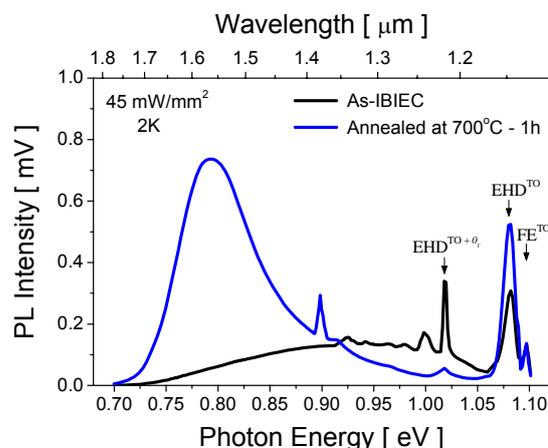


Figure 2: PL spectra (at 2 K) presented a prominent band at \sim 0.79 eV (700 °C annealed sample) beyond of excitonic complex emissions from Si substrate (also observed in the as-IBIEC sample).